

MAY 24 2006

PATENT
Atty. Dkt. No. APPM/008245/DSM/BCVD/JP

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:
Wang, et al.

Serial No.: 10/800,112

Confirmation No.: 8920

Filed: March 12, 2004

For: Method of Depositing an
Amorphous Carbon Film
For Metal Etch Hardmask
Application

Group Art Unit: 1765

Examiner: Mahmoud Dahimene

MAIL STOP AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450CERTIFICATE OF FACSIMILE TRANSMISSION UNDER
37 CFR 1.8

I hereby certify that this correspondence and the documents referred to as attached therein are being facsimile transmitted to the U.S. Patent and Trademark Office to the fax number indicated by the Examiner, namely, fax number (571) 273-8300 to the attention of the named Examiner, on the date below.

5/24/06

KJZ 24
Signature

Dear Sir:

RESPONSE TO FINAL OFFICE ACTION DATED APRIL 5, 2006

In response to the Final Office Action dated April 5, 2006, having a shortened statutory period for response set to expire on July 5, 2006, please enter this response and reconsider the claims pending in the application for reasons discussed below. Although Applicants believe that no additional fees are due in connection with this response, the Commissioner is hereby authorized to charge counsel's Deposit Account No. 20-0782/APPM/008245/KMT, for any fees, including extension of time fees or excess claim fees, required to make this response timely and acceptable to the Office.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper. **Remarks** begin on page 7 of this paper.